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Quality Control by Artificial Vision

Jean-Charles Pinoli
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Editors

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Introduction

The research group on Image and Pattern Processing, Analysis and Modeling of the LPMG/CNRS-ENSMSE is proud to welcome the Tenth International Conference on Quality Control by Artificial Vision to Saint-Etienne. QCAV 2011 follows several worldwide editions – France in 1993, 1995, 1997, 2001, 2007, Japan in 1998 and 2005, Canada in 1999, the USA in 2003, and Austria in 2009.

Twenty-four papers have been selected by the international scientific committee (from which two are for the poster session) from Austria, France, Germany, Japan, Tunisia, and the United Kingdom. Moreover, three keynote speakers, renowned in the field of image processing and quality control, honoring us with their presence: Claude Lambert from the ENSM-SE and CHU-SE (France), Seiji Hata from the Kagawa University (Japan), and Fabrice Mériaudeau from the University of Burgundy (France).

It is our pleasure to say that a special section of the *Journal of Electronic Imaging* (copublished by SPIE and IS&T) will be dedicated to QCAV 2011 and will feature selections based on the best papers presented at the conference.

This year's conference is supported by SPIE as a cooperating organization. The organizing committee is very grateful to them for trusting us, and would also like to acknowledge our partners and sponsors for their precious help in organizing the conference:

- Ecole Nationale Supérieure des Mines de Saint-Etienne (France)
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Jean-Charles Pinoli
QCAV 2011 Conference Chair